

Advances in

**OPTICAL and ELECTRON  
MICROSCOPY**

Volume 9

Edited by

**R. BARER**

**AND**

**V. E. COSSLETT**

*Advances in*

# OPTICAL *and* ELECTRON MICROSCOPY

*Volume 9*

*Edited by*

R. BARER

*Department of Anatomy and Cell Biology,  
University of Sheffield, England*

AND

V. E. COSSLETT

*High Resolution Electron Microscopy Laboratory,  
University of Cambridge, England*



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## Contributors List

- C. COLLIEX, *Laboratoire de Physique des Solides, Université Paris-Sud 91405, Orsay, France.*
- K. H. HERRMANN, *Fritz-Haber-Institut der Max-Planck-Gesellschaft, Abt. Elektronenmikroskopie, D-1000 Berlin 33 (Dahlem), Germany.*
- R. L. HINES, *Department of Physics and Astronomy, Northwestern University, Evanston, Illinois 60201, USA.*
- D. KRAHL, *Fritz-Haber-Institut der Max-Planck-Gesellschaft, Abt. Elektronenmikroskopie, D-1000 Berlin 33 (Dahlem), Germany.*
- L. MOENKE-BLANKENBURG, *Sektion Chemie der Martin-Luther-Universität, Halle-Wittenberg, DDR-4020 Halle, GDR.*
- D. ROSEN, *Department of Biophysics and Bioengineering, Chelsea College, London SW3 6LX, UK.*
- F. H. SMITH, *Vickers Instruments, York, UK.*

## Preface

Methods for the microscopic examination of matter continue to expand in both their variety and their complexity. Before we have had time to evaluate fully the scanning optical and the photo-electron microscopes, the scanning electron-acoustic instrument is with us. The Auger micro-analytical method has developed a visual display system and it may not be long before laser-excited "destructive analysis" does likewise. It is a teasing question as to how far these techniques should be covered in this series. They all involve beams of light or electrons in one way or another. We can no longer appeal to the simple idea that a microscope includes lenses as essential components of an imaging system.

The solution must be to await substantial advances in a subject, in its performance and applications, before including it, and at the same time to increase the frequency of publication, which we hope to do. To assist in this task we now have two Assistant Editors and an Editorial Board; their names are given opposite the title-page.

Articles for future volumes have already been commissioned on the following subjects:

- Auger Microscopy
- High Resolution Electron Microscopy
- Field Ion Microscope
- Calculation of Structure Images in Electron Microscopy
- Photographic Emulsions for Electron Microscopy
- The Early History of the Electron Microscope
- Holographic Microscopy
- Contact Microscopy
- Acoustic Microscopy
- Scanning Optical Microscopy

Other subjects are under discussion. Suggestions are invited for topics (and authors) in any relevant fields of microscopy.

The present volume continues the established pattern of three articles in each division of microscopy, optical and electron. In the latter, a full account is given of electronic image recording in the conventional EM, as distinct from the scanning instrument. The theoretical limitations as well as the present state of instrumentation are presented in detail by Herrmann and Krahl, from a laboratory with great experience in the subject. The inclusion of energy loss spectroscopy might have been considered a marginal decision a

few years ago. Now it is an essential component of the analytical electron microscope in so many branches of materials science, and in addition, techniques for forming filtered images have been devised. The article by Colliex, one of the earliest and most active workers in the field, provides an authoritative and up-to-date review of it. The third article, by Hines, considers the special problems of high resolution electron microscopy. It is particularly valuable since it is concerned with those problems encountered in the running of a normal high grade instrument, not with one custom-built for the highest possible resolution. The title could equally well have been "how to get the best performance from your EM".

Optical articles cover a wide range of topics. Laser microanalysis, reviewed by Lieselotte Moenke, a pioneer in the field, is now a widely accepted and valuable technique. The development of binocular image-shearing microscopes is described by F. H. Smith. Such instruments have achieved a striking success particularly in the microchip industry. Finally, Rosen reviews some of the image analyser systems now available commercially. He gives a broad account of some basic problems which should perhaps correct some of the over-enthusiastic claims in some manufacturer's brochures.

As happened on a previous occasion, circumstances outside the control of the editors have caused some delay in the publication of particular articles and resulted in the reversal of the two divisions of our subject matter.

*May 1984*

R. BARER.  
V. E. COSSLETT.

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# Electronic Image Recording in Conventional Electron Microscopy

K.-H. HERRMANN\* and D. KRAHL

*Früz-Haber-Institut der Max-Planck-Gesellschaft, Abt. Elektronenmikroskopie,  
D-1000 Berlin 33 (Dahlem), Faradayweg 4-6, Germany*

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## LIST OF SYMBOLS

$a$  local extension of single-electron signal (in TV lines)

$$A = \frac{f}{e \cdot 12 \text{ MHz}}$$

$B$  subtracted constant level in digital storage

\* Present address: Institut für angewandte Physik der Universität Tübingen D-7400 Tübingen Auf der Morgenstelle 10, Germany.

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$c$	speed of light
$C = \frac{\Delta q}{q}$	image contrast
$d$	linear dimension of an image detail
$D_s = S_{\max} / \sqrt{\Delta S^2}$	dynamic range of analog storage
DQE	detection quantum efficiency
$e$	elementary charge
$E$	electron energy in first-generation intensifiers
$E_0$	energy of primary electrons
$E_{BS}$	energy of backscattered electrons
$E_F$	mean formation energy per charge carrier
$\Delta E$	absorbed electron energy in first converter stage
$f$	processed image field at intensifier input
$f'$	partial area of processed image field
$F$	$F$ -number of light optical systems
$g$	gain of system scintillator—light optics—photocathode
$g_P$	photon gain of intensifiers
$g_T$	target gain in camera tubes
$g_v$	quantum yield of converter stage $v$
$G$	spectral matching factor scintillator—photocathode
$h$	Planck constant
$I$	signal current of camera tube
$I_m$	maximum signal current of camera tube
$\overline{I_N^2}$	mean noise square of video readout and amplification process
$j$	current density at image converter input
$j_0$	current density in object plane of the electron microscope
$j_m$	overmodulation limit of current density
$\bar{k}$	mean exposure of a detector array
$\bar{l}$	mean counting response of a detector array
$L$	word length of pixel storage capacity
$m$	temporal extension of single electron signal (half frames)
$M$	magnification
$n_e = j/e$	pulse density rate of electrons

$n_0$	refractive index of scintillator
$n_1, n_2$	refractive index of fibre core resp. case
$n_B$	background pulse density rate
$\overline{n_E^2}$	electron noise equivalent of target readout process
$n_{\min}$	minimum detectable single electron signal on the target
$n_{PE}$	number of photoelectrons
$n_P$	number of photons
$n_r$	pixel number per unit cell
$n_T$	number of charge carriers representing the single primary electron on the target
$N$	number of electrons
$N_B$	number of background counts
$N_D$	pixel number per unit cell
$N_e$	number of processed unit cells
$N_m$	counting limit of digital storage
$N_p$	linear pixel number of digital storage
NA	numerical aperture
$p(n)$ $v(n)$	probability distribution of stochastic variable $n$
$P(z)$ $V(z)$	generating functions of distributions $p(n), v(n)$
$q$	charge density
$q_{\max}$	maximum charge density corresponding to upper exposure limit of a storage
$s$	size of single-electron signal
$s_B$	size of background signal
$s_E$	single-electron video signal
$s(\lambda)$	spectral response of camera tubes
$S$	signal
$S_{\max}$	upper exposure limit of analog storage
$S_N$	video noise contribution to the output signal referred to the target
SNR	signal-to-noise ratio
$SNR_m$	maximum signal-to-noise ratio

$\overline{\Delta S^2}$	mean squared noise of analog storage
$t$	total accumulation time
$t'$	total scanning time of a partial area $f'$
$\Delta t$	total readout time of single electron signal
$T$	transmission factor of light optical systems
$U$	converter voltage of camera tubes
$N^2$	number of resolved image elements in digital storage
$Z$	atomic number
$\alpha_0$	collected half angle in the scintillator
$\alpha_1$	acceptance half angle of light optical system
$\alpha_i$	illumination aperture
$\beta$	gun brightness
$i$	slope of a recorder
$\delta_P$	pixel size at image converter input
$\epsilon$	energy conversion coefficient of cathodoluminescence
$\eta$	fraction of utilized electrons
$\eta_B$	fraction of counted background signals
$\eta_{BS}$	backscattering coefficient
$\eta_f$	collection efficiency of light optical system
$\eta_{PC}(\lambda)$	quantum yield of photocathode
$\eta_t(\lambda)$	quantum yield of camera tube
$\kappa$	matching factor between charge density $q$ and signal $S$ in analog storage systems
$\lambda$	wave length of light
$\nu$	frequency of light
$\tau$	frame time
$\Omega$	total collected solid angle in the scintillator

## I. INTRODUCTION

The conventional transmission electron microscope as well as various other imaging electron beam devices produce information on the specimen as a two-dimensional electron current density distribution. In order to observe, record and evaluate this electron image, it is converted by means of sensors into a suitable form and conserved in a storage medium (Fig. 1) which not

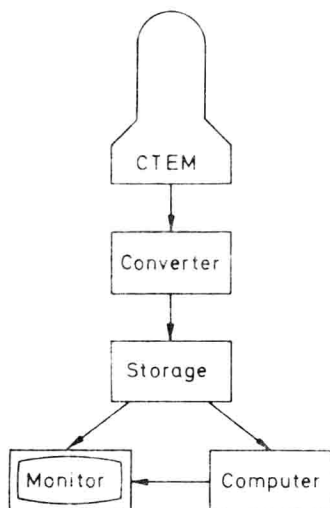


FIG. 1. Scheme of information processing.

only holds the information but performs statistical averaging. The photoplate combines both functions. From the beginning of electron microscopy, the photoplate has been the favoured medium for registration, and it can hardly be surpassed as to number of image elements and simplicity of handling. A serious disadvantage, the long processing time, has led to the development of more sophisticated devices which carry out the recording in "real time". Partition of their function into "information conversion" and "information storage" steps allows both a high degree of flexibility and immediate "on-line" image processing (Fig. 1). Here, electronic image recording systems operating with TV techniques offer good prerequisites within the number of image elements given by TV standards; the connected frame stores can operate analogously and digitally.

For some time, TV image intensifiers have been simply an aid to observation of low-intensity electron images, for which various reasons are responsible. The final current density of an electron microscope is connected with the current density  $j_0$  in the object plane via the relation

$$j = \frac{j_0}{M^2} \quad (1)$$

where  $M$  is the electron optical magnification. In the bright-field mode, the current density  $j_0$  is, according to

$$j_0 = \pi \beta \alpha_i^2 \quad (2)$$



given by the gun brightness  $\beta$  and the illumination aperture  $\alpha_i$ . Current densities below  $1 \text{ pA cm}^{-2}$  in the final plane are therefore encountered, for example, when microscopy is done with approximately coherent illumination ( $\alpha_i < 10^{-4}$ ) with thermionic beam sources ( $\beta = 4 \times 10^5 \text{ A cm}^{-1} \text{ sr}^{-1}$  at 100 keV electron energy). Even more unfavourable is the situation in the darkfield mode or when imaging with energy filters if microscopy is done exclusively with elastically or inelastically scattered electrons. Often the thermal sensitivity of the specimen restricts the permissible object current density. But also in several other instruments or procedures, the yield of imaging electrons is limited for different reasons (e.g. photoemission microscopy, reflection microscopy with diffracted beams). Since the resolving power of the eye decreases considerably with decreasing image brightness (Schober, 1970), image observation with the systems screen-eye or screen-light optics-eye does not allow a sufficient detail detectability at low current density. Image intensifier tubes (Nirikoff *et al.*, 1958) or low-light-level TV techniques (Herrmann and Krahl, 1973) eliminate this restriction by offering to the eye the image at a higher brightness level.

In order to compete with photographic recording, however, such systems would have to be able to integrate the signal, because at current densities below  $10 \text{ pA cm}^{-2}$  the electron statistics is already distinctly visible. Indeed, the storage time is, by means of long-persistence monitors, prolonged up to about 2 s compared to the usually decisive storage time of the eye (0.2 s), thus obtaining a certain averaging of the statistic fluctuations. A fully satisfying recording system is, however, only achieved if the storage time of the accumulator can be chosen arbitrarily and if its standby-time for a subsequent—not necessarily visual—evaluation is sufficiently long. The production of such electronic recording systems is under way and some are already in operation. Their aim is not only to improve the observation of the final image in order to adjust the microscope exactly for subsequent photographic recording but also to permit the computational on-line image processing, which has, up to now, mostly been carried out off-line by digitizing the photoplate transparency via a scanning photometer.

The importance of electronic recording systems and the requirements for these come to light in an application area which reveals the present limitations of high resolution electron microscopy. Radiation sensitivity, particularly of molecular-biological specimens, prevents their imaging in an undamaged state. Damage-free imaging is only possible, if at all, by minimum-exposure technique (Williams and Fisher, 1970) and by cryo-electron microscopy (Knapik and Dubochet, 1980) with low-dose images, where preirradiation is avoided and a compromise made between image quality and damage probability. Corresponding electronic control of the specimen irradiation is provided in modern electron microscopes. Since an